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Substitute for form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				APPLICATION NUMBER	10/747,737
				FILING DATE	12/29/2003
				FIRST NAMED INVENTOR	Bailey et al.
				Group Art Unit	1756
				Examiner Name	Unassigned
Sheet	4	of	7	Attorney Docket Number	PA97-39D13D21

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	† ²
		Office	Number ³				

EC	C47	WO	00/21689		Chou et al.	4/20/2000	
	C48	JP	02-02603		Kurikawa et al.	4/31/1990	
	C49	JP	02-24848		Kamio	1/28/1990	
	C50	WO	01/47003		Steiner et al.	6/28/2001	
	C51	WO	02/07199		Chou	1/24/2002	
	C52	WO	2004/114018		Chou et al.	12/29/2004	
	C53	WO	99/05724		Chou et al.	2/4/1999	
	C54	WO	03/010289		Chou et al.	2/8/2003	
	C55	WO	03/079416		Chou	9/25/2003	
EC	C56	WO	03/099538		Chou et al.	12/4/2003	

Examiner Signature		Date Considered	5/15/06
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ³

EL	C57	Chou, Nanoimprint Lithography and Lithographically Induced Self-Assembly, MRS Bulletin, pp. 512 - 517, 7/1/2001	
	C58	Choi et al., Design of Orientation Stages for Step and Flash Imprint Lithography, Precision Engineering, pp. 192 - 199, 1/1/2001	
	C59	Colburn et al., Step and Flash Imprint Lithography for sub-100 nm Patterning, Proceedings of SPIE Vol. 3997, pp. 453 - 457, 1/1/2000	
	C60	Chou et al., Imprint Lithography with 25-Nanometer Resolution, Science Vol. 272, pp. 85 - 87, 4/5/1996	
	C61	Chou et al., Imprint Lithography with Sub-10 nm Feature Size and High Throughput, Microelectronic Engineering 35, pp. 237 - 240, 1/1/1997	
	C62	Haisma et al., Mold-assisted Nanolithography: A Process for Reliable Pattern Replication, J. Vac. Sci. Technol. B, pp 4124 - 4128, 11/1/1996	
	C63	Chou et al., Imprint of Sub-25 nm Vias and Trenches in Polymers, Appl. Phys. Lett. 67 (21), 11/20/1995	
	C64	Johnson et al., Advances in Step and Flash Imprint Lithography, SPIE Microlithography Conference, 2/23/2003	
EL	C65	Chou et al., Lithographically Induced Self-assembly of Periodic Polymer Micropillar Arrays, J. Vac. Sci. Technol. B 17 (6), pp. 3197 - 3202, 11/1/1999	

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